

## Internship – Projects Overview

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  - 10/6/2011

## Project 1 : Multi-Trend 2

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- Purpose: Rewrite the Multi-Trend Program, which was originally written as a Visual Basic macro for MS Excel, to a standalone C# program
- Background: Multi-Trend is a Statistical Analysis Program looking at Cpk trends
- Requirements:
  - C#
  - Original Functionality
  - Added Functionality
  - Time Constraints
  - Clear Coding
  - Full Documentation

## Background

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- > Cpk: Indicates how many times you can fit three standard deviations of the process between the mean of the process and the nearest specification limit. (Wikipedia)
- > Basically, this tells you how centered the mean of the process is compared to ideal conditions.
- > Example: Upper Limit = 4, Lower Limit = 2; Mean ideally would be 3. Cpk looks at how close the reality is to the ideal.

## How is this accomplished?

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- > Parametric Testing data is stored on an SQL server
- > Testing Parameters are stored by a Technology type and a Name
- > After the user selects the options from the main GUI, the SQL server is queried for data
- > An Excel spreadsheet is generated with the downloaded data
- > This data is analyzed
- > If the Cpk of the parameter is below 1.67, the parameter needs to be looked at, and its data points are plotted.



Select a Technology ▾

Delete File

Select Parameters to Load ▾

# of Params

## Available Parameters

Add -&gt;

Remove &lt;-

Add All  
Selected

Add All -&gt;

## Selected Parameters

Clear List

Delete

Move Up

Move  
DownEdit  
Selected  
Parameter

Save Selected Parameters

## Data Options

- ☐ Lot Averages
- ☐ Wafer averages
- ☒ Individual Points

## Filter Options

- ☐ Filter on Screen Limits
- ☒ Filter on Spec Limits
- ☐ Filter on +/-  % Limits
- ☐ Do not filter data

## Query Options

Start Date  /  /

▾

Stop Date  /  /

▾

☒ Show Monthly Data

## Current User :

Default

OK

Cancel

Reset

Load User

Create User

Default Settings

## Other Options

- ☐ Cpk Frontpage
- ☐ Plot CP / CPK Results
- ☐ Plot All Parameters (Max = 80)
- ☐ Disable Plotting

## Specify Devices (optional)

Add Device

Remove Device

- ☐ Plot by Date
- ☒ Plot by Lot #
- ☐ Plot by Wafer #
- ☐ Plot by Site #
- ☐ Plot by Device

[illegible]



# Project Results

## > Requirements

- Language: C#
- Original Functionality Kept
- New functionality Added
- Easy to Use
- Full Documentation
- Clear Coding
- Timeline: By July 27<sup>th</sup>  
(End of Program)

## End-Product

- ✓ Language: C#
- ✓ Original Functionality  
Successfully maintained
- ✓ Many New Functions Added
- ✓ Easy GUI for low learning  
Curve
- ✓ Full Documentation:  
Readme.txt  
Code Supplement.txt
- ✓ Clear Coding: Full  
documentation and  
formatting
- ✓ Completed By July 4th

Conclusion: Project Successful



## Project 2: Mapconvert

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- > Purpose: Write a Program that can convert XFab Internal Wafer Map formats to Industry standards and then back again.
- > Background: Up until this point, no program of this type has existed.

# Project Requirements

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- > Cross Platform C++
- > Command Line Required, GUI Optional
  - GUI not necessary, program operation relatively short
- > SEMI <-> TH01
- > SEMI <-> TH02
- > Clear Detailed Comments
- > User Documentation
- > Converted Files must read correctly into the wafer map viewer programs.

## Background Information

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- > TH0X Formats are Binary Files (no character Delimiters)
- > Semi Standard written in XML
- > TH02 is a modified TH01 with a longer header
- > Wafer Maps are a graphical representation of a Wafer's Pass/Fail characteristics of it's dice.
- > Files consist of Headers containing important information followed by die data.



Information (I), Warnings (W) &amp; Error messages (E)

I -- authorized as SDA/X user.  
I -- cache manager available.  
I -- Welcome to the WmapMasterDataService provided by Melexis.  
I -- Here we go again!

Lot/Wafer selection

M Lot	Wf Rp	Device	Date	Time	Meas. program	Test variant	Map file
C T117							
C T084							

Zoom [%]

100

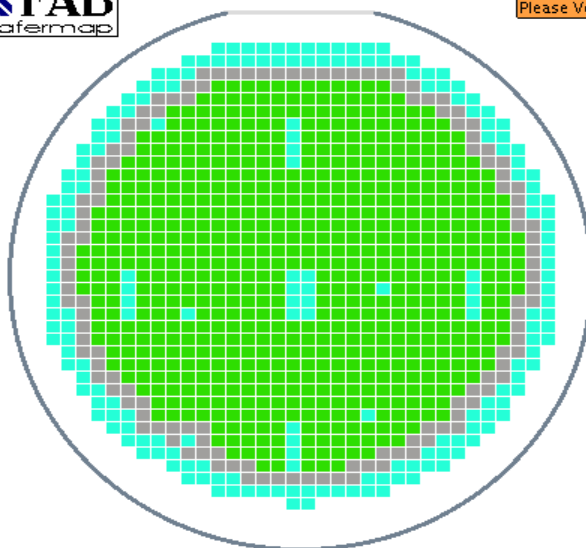
Lot/Wafer pre



Wafermap

Reliability Inked  
Please Verify!

Type: ME15120DE\_NE  
Lot: T11562  
Wafer: 03  
Date: 09.07.07 17:07  
Yield: 67.5 %



200	0
681	1
0	2
0	3
0	4
0	5
0	6
0	7
0	8
0	9
0	10
0	11
0	12
0	13
0	14
0	15
0	16
0	17
0	18
0	19
0	20
0	21
0	22
0	23
0	24
0	25
0	26
0	27
0	28
128	29

General Advanced Technology Directory

Filter setup

- ☒ Database location
- ☒ Wafermap type
- ☐ Kind of meas.
- ☐ Device name
- ☐ Lot ID
- ☐ Meas. program
- ☐ Test variant
- ☐ Tester
- ☐ Meas. period

Erfurt (hot)

only category r

(1) Chip test

degbitv

degbitv

degbitv

degbitv

Par.-Tester

25 07 20

files found: 6 ☐ disable Timeout

RIP Menu

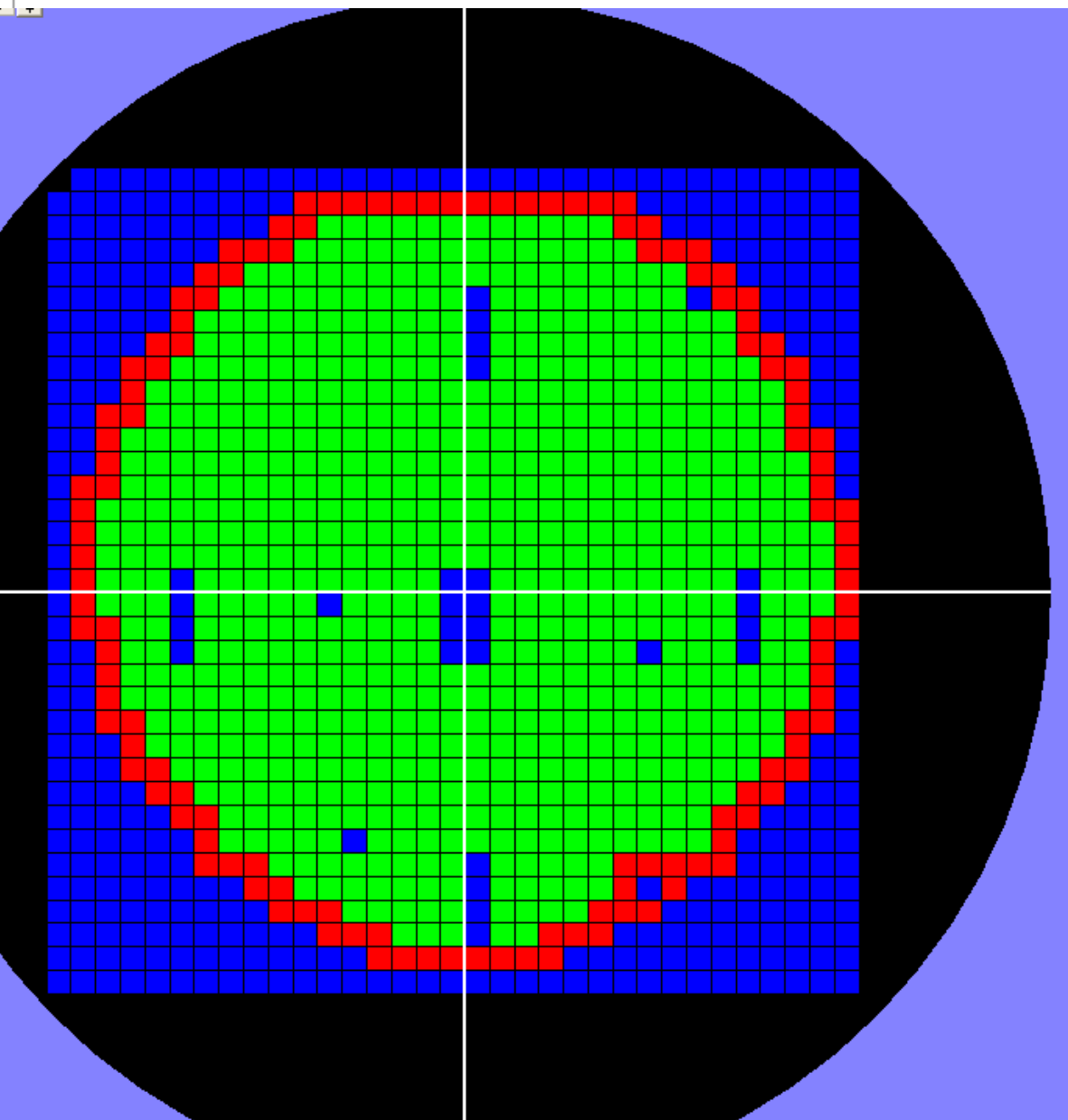
Close




Filter

Continue

Close

Close





011001  
111001  
001011  
101101

Open FileDescriptionBins EditExit

Open as FormatSemi\_0703Open

Index File NameC:\Documents and Settings\x1389\Desktop\ripped.xml

Lots

Wafers

T11562 -03

☒ Show Reference DieFlat Position : Bottom

	Bin	Name	Count	Status
Green	32		681	Good
Red	71		128	Defect

All Dies : 809 Good 681 Bad 128

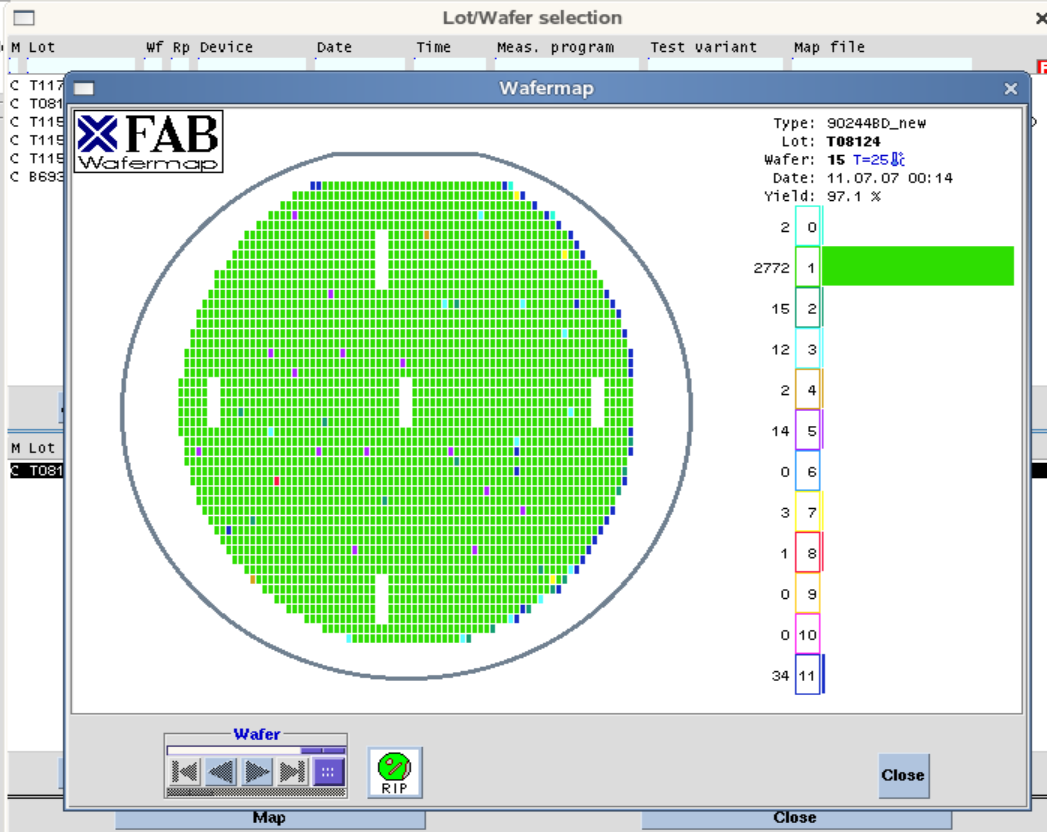
File Map ! Lists Output Setup Options Calculations Log Info Extras

Help



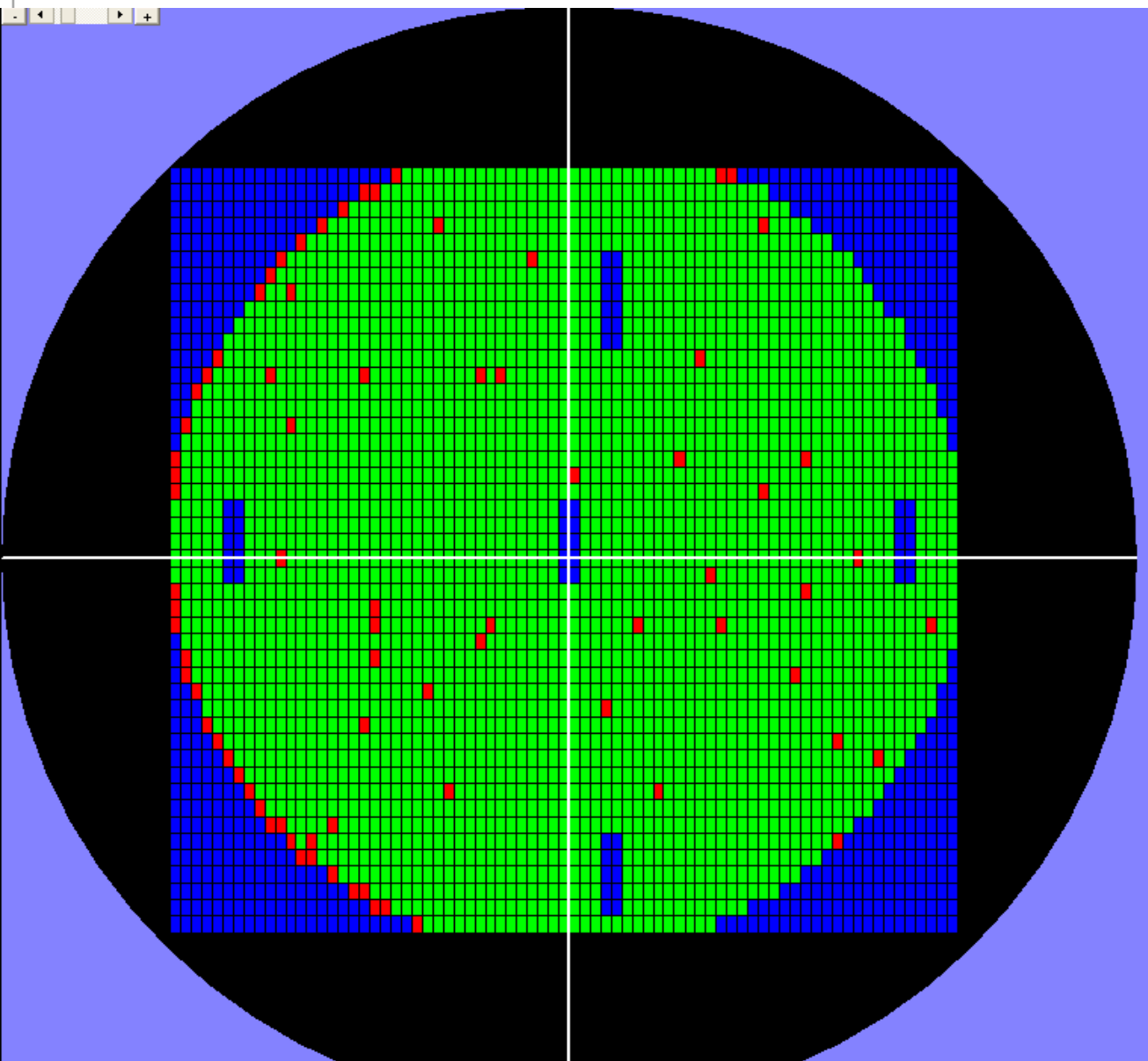
Information (I), Warnings (W) &amp; Error messages (E)





I -- authorized as SDA/X user.  
I -- cache manager available.  
I -- Welcome to the WmapMasterDataService provided by Melexis.  
I -- Here we go again!



Zoom [%]

100





Open File   Description   Bins Edit   Exit

Open as Format   Semi\_0703   Open



Index File Name   C:\Documents and Settings\x1389\Desktop\c

Lots

Wafers

T08124   -15

☒ Show Reference Die   Flat Position : Bottom

	Bin	Name	
	32		
	71		

All Dies : 2826 Good 2748 Bad 78

# Project Assessment

Required

Actual

- > Cross Platform C++
- > Command Line Required, GUI Optional
  - GUI not necessary, program operation relatively short
- > SEMI <-> TH01
- > SEMI <-> TH02
- > Clear Detailed Comments
- > User Documentation
- > Converted Files must read correctly into the wafer map viewer programs.

- > Cross Platform C++
- > Command Line interface with minimal User Interface
- > SEMI <-> TH01
- > SEMI <- TH02
- > Full Commenting
- > Readme documentation
- > All files read correctly after conversions.

Project Successful



# Internship Summary

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- > All projects successful and on-time
- > Results presented to Texas Tech College of Engineering
- > Intern was hired on as contract worker with a title of Software Development Engineer.